

Form PTO 1449  U.S. Department of Commerce Patent and Trademark Office  Information Disclosure Statement by Applicant	ATTY. DOCKET NUMBER HITA-0458	SERIAL NUMBER To be assigned - 10/71271
	APPLICANT SATO et al	
	FILING DATE Concurrently herewith	GROUP 285 2812

U.S. Patent Documents

Examiner Initial	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE

Foreign Patent Documents

Examiner Initial	DOCUMENT NUMBER	FILING DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
OL	6-140323	10/23/92	Japan			Abstract	X
OL	2001-274088	5/28/96	Japan			Abstract	X
OL	2002-280302	3/16/2001	Japan			Abstract	X

Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)

OL	Chang-ho Oh and Masakiyo Matsumura, "Preparation of Position-Controlled Crystal-Silicon Island Arrays by Means of Excimer-Laser Annealing", Jpn. J. Appl. Phys., Vol. 37 (1998) pp. 5474-5479
OL	Do-Hyun Choi, Kazuhiro Shimizu, Osamu Sugiura and Masakiyo Matsumura, "Drastic Enlargement of Grain Size of Excimer-Laser-Crystallized Polysilicon Films", Jpn. J. Appl. Phys., Vol. 31 (1992) pp. 4545-4549
OL	Koichi Murakami, Tetsuo Takahashi, Tadamas Koyanagi, Koichiro Hoh, Yoshio Komiya and Yasuo Tarui, "Thermal Analysis and Experimental Evaluation of Melting Threshold Energy of Si Thin Film Structure in Laser Annealing" Japanese Journal of Applied Physics, Vol. 21, No. 6, June 1982, pp. 879-884
EXAMINER	DATE CONSIDERED
<i>Olivia Burt</i>	3/28/05
EXAMINER: Initial if citation is considered, whether or not citation is in conformance with MPEP 609; draw a line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant	